China

OPTO-EDU

CE, Rohs

A62.4511

5000 pcs/ Month

1pc

Opto Edu A62.4511 Scanning Microscope Contact Tapping Mode Plane Atomic Force

FOB \$1~1000, Depend on Order Quantity

Carton Packing, For Export Transportation

Basic Information

- Place of Origin:
- Brand Name:
- Certification:
- Model Number:
- Minimum Order Quantity:
- Price:
- Packaging Details:
- Delivery Time:
- 5~20 Days • Payment Terms: L/C, T/T, Western Union
- Supply Ability:



0

Product Specification

Work Mode:	"Contact Mode Tapping Mode Optional Friction Mode Phase Mode Magnetic Mode Electrostatic Mode"
Current Spectrum Curve:	"RMS-Z Curve F-Z Force Curve"
• XY Scan Mode:	Sample Driven Scanning, Closed Loop Piezoelectric Shift Scanning Stage
• XY Scan Range:	Closed Loop 100×100um
• XY Scan Resolution:	Closed Loop 0.5nm
• Z Scan Range:	5um
 Z Scan Resolution: 	0.05nm
• Scan Speed:	0.6Hz~30Hz
 Scan Angle: 	0~360°
 Sample Weight: 	≤15Kg
Stage Size:	"Dia.100mm Optional Dia.200mm Dia.300mm"
 Stage XY Moving: 	" 100x100mm, Resolution 1um Optional

Our Product Introduction

Plane Scanning Atomic Force Microscope

Gantry scanning head design, marble base, vacuum adsorption stage, sample size and weight are basically unlimited A62.4510 + Closed-loop three-axis independent pressure shift scanner, which can scan with high precision in a wide range Intelligent needle feeding method with automatic detection of motor-controlled piezoelectric ceramics to protect probes and samples Automatic optical positioning, no need to adjust focus, real-time observation and positioning probe sample scanning area Equipped with closed metal shield, pneumatic shock-absorbing table, strong anti-interference ability



A62.4511 Plane Scanning Atomic Force Microscope (AFM)



Product Details

• The first commercial atomic force microscope in China to realize combined mobile scanning of probe and sample;

• The first in China to use a three-axis independent closed-loop piezoelectric shift scanning table to achieve large-scale high-precision scanning;

• Three-axis independent scanning, XYZ does not affect each other, very suitable for three-dimensional material and topography detection;

• Electric control of sample moving table and lifting table, which can be programmed with multi-point position to realize fast automatic detection;

• Gantry scanning head design, marble base, vacuum adsorption and magnetic adsorption stage;

• The motor automatically controls the intelligent needle feeding method of the piezoelectric ceramic automatic detection to protect the probe and the sample;

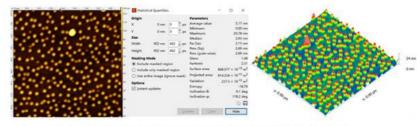
• High magnification auxiliary optical microscope positioning, real-time observation and positioning of probe and sample scanning area;

 The closed-loop piezoelectric scanning stage does not require nonlinear correction, and the nanometer characterization and measurement accuracy is better than 99.5%.





Sapphire epitaxial wafer/scanning range 1 $\mu m \times$ 1 $\mu m/Sa$ =1.7 nm, Sq =2.08 nm



GaAs wafer/scanning range 0.9 $\mu m \times$ 0.9 $\mu m/Sa=2.15 nm, Sq=2.69 nm$

Specification



	A62.4510	A62.4511				
	Contact Mode	Contact Mode Tapping Mode				
	Tapping Mode					
Work Mode	Optional	Optional				
WORK WIDDE	Friction Mode	Friction Mode Phase Mode Magnetic Mode Electrostatic Mode				
	Phase Mode					
	Magnetic Mode					
	Electrostatic Mode					
Current Spectrum Curve	RMS-Z Curve	RMS-Z Curve				
	F-Z Force Curve	F-Z Force Curve				
XY Scan Mode	Probe Driven Scanning,	Sample Driven Scanning, Closed Loop				
AT Scall Mode	Piezo Tube Scanner	Piezoelectric Shift Scanning Stage				
XY Scan Range	70×70um	Closed Loop 100×100um				
XY Scan Resolution	0.2nm	Closed Loop 0.5nm				
Z Scan Mode		Probe Driven Scanning				
Z Scan Range	5um	5um				
Z Scan Resolution	0.05nm	0.05nm				
Scan Speed	0.6Hz~30Hz	0.6Hz~30Hz				
Scan Angle	0~360°	0~360°				
Sample Weight	≤15Kg	≤0.5Kg				
1 0	Dia.100mm	Dia.100mm				
Stage Size	Optional	Optional				
	Dia.200mm	Dia.200mm				
	Dia.300mm	Dia.300mm				
	100x100mm, Resolution 1um	100x100mm, Resolution 1um				
Stage XY Moving	Optional	Optional				
	200x200mm	200x200mm				
	300x300mm	300x300mm				
	15mm, Resolution 10nm	15mm, Resolution 10nm				
	Optional	Optional				
Stage Z Moving	20mm	20mm				
	25mm	25mm				
	Spring Suspension	Spring Suspension				
Shock-Absorbing Design						
Shock-Absorbing Design	Optional	Optional				
	Active Shock Absorber	Active Shock Absorber				
	Objective 5x	Objective 5x				
	5.0M Digital Camera	5.0M Digital Camera				
Optical System						
	Optional	Optional				
	Objective 10x	Objective 10x				
-	Objective 20x	Objective 20x				
Output	USB2.0/3.0	USB2.0/3.0				

Software	e	Win X						(P/7/8/10 y Scan Head, Marble Base			
Main Bo	dy	Gantry									
Microsco	оре	Optical Microscope			Electron Micr	Electron Microscope		Scanning Probe Microscope			
Max Resolution (um) 0.18		0.000		.00011		0.0008					
Oil immers		mmersio	on 1500x	Imaging diam atoms			Imaging high-order graphitic carbon atoms				
Remark											
Probe-Sample Interaction			Measure Signal			Information					
Force			Electrostatic Force			Shape					
Tunnel Current			Current			Shape, Conductivity					
Magnetic Force			Phase			Magnetic Structure					
Electrostatic Force			Phase			charge distribution					
	Resolution		Workin	g Condition	Working Tempe	ration	Damge to	Sample	Inspection Depth		
SPM	Atom Level	0.1nm	Normal, Liquid, Vacuum		Room or Low Temperation		None		1~2 Atom Level		
ТЕМ	Point 0.3~0. Lattice 0.1~(High Vaccum		Room Tempera	tion	Small		Usually <100nm		
SEM	6-10nm		High Vaccum		Room Tempera	tion	Small		10mm @10x 1um @10000x		
FIM	Atom Level	.1nm Super High V		High Vaccum	30~80K		Damge		Atom Thickness		

System Diaphragm

